

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Gabric, <i>et al.</i>	Docket No.:	INF 2006 VJ 33543 US
Serial No.:	10/586,788	Art Unit:	2893
Filed:	September 2, 2008	Examiner:	Nikolay K. Yushin
		Conf. No.:	1598
For:	Plasma Excited Chemical Vapor Deposition Method Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly		

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's
Office Action mailed June 4, 2009. Please amend the above-referenced application as follows.